

Abstract of the Disclosure

A dividing plate for a thin-film deposition apparatus divides the interior of the vacuum reaction chamber into a plasma discharge space and a film deposition process space, by fixing or connecting a plurality of laminated plates together by securely bonding them over the entire area of their interfacial surfaces, or a large portion thereof.

1. A dividing plate for a thin-film deposition apparatus, comprising a plurality of laminated plates, each having a first surface and a second surface, the first surface of each plate being bonded to the second surface of an adjacent plate, the bonding being over the entire area of the interfacial surfaces, or a large portion thereof, to form a dividing plate.